

Electronic Patent Application Fee Transmittal

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|---|---|-----------------|---------------|-----------------------------|
| Application Number: | 10586788 | | | |
| Filing Date: | | | | |
| Title of Invention: | Plasma excited chemical vapor deposition method, silicon/oxygen/nitrogen-containing-material and layered assembly | | | |
| First Named Inventor/Applicant Name: | Zvonimir Gabric | | | |
| Filer: | Ira Stuart Matsil/Nancy Milinkovich | | | |
| Attorney Docket Number: | INF 2006 VJ 33543 US | | | |
| Filed as Large Entity | | | | |
| U.S. National Stage under 35 USC 371 Filing Fees | | | | |
| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
| Basic Filing: | | | | |
| Pages: | | | | |
| Claims: | | | | |
| Miscellaneous-Filing: | | | | |
| Oath/decl > 30 months from priority date | 1617 | 1 | 130 | 130 |
| Eng. Transl. > 30 mo. from priority date | 1618 | 1 | 130 | 130 |
| Petition: | | | | |
| Patent-Appeals-and-Interference: | | | | |
| Post-Allowance-and-Post-Issuance: | | | | |

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
|--------------------|----------|----------|--------|----------------------|
| Extension-of-Time: | | | | |
| Miscellaneous: | | | | |
| Total in USD (\$) | | | | 260 |